



Appl. No. 09/937,538
Amdt. Dated March 5, 2004
Reply to Office Action of December 8, 2003

Attorney Docket No. 81839.0102
Customer No.: 26021

RECEIVED

MAR 11 2004

Technology Center 2100

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Michihiro MIZUNO

Serial No: 09/937,538

Confirmation No.: 2057

Filed: September 25, 2001

For: METHOD FOR EVALUATING
CONCENTRATION OF METALLIC
IMPURITIES IN SILICON WAFER

Art Unit: 1743

Examiner: Siefke, Samuel P.

I hereby certify that this correspondence
is being deposited with the United States
Postal Service with sufficient postage as
first class mail in an envelope addressed
to:

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 5, 2004

Date of Deposit

John P. Scherlach, Reg. No. 23,009

Name

John P. Scherlach 03/05/04

Signature

Date

AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action of December 8, 2003, please amend the
above-referenced application as follows:

Amendments to the Claims are reflected in the Listing of Claims, which
begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.